

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of: )  
)  
MUNEHIRO OGASAWARA ET AL. )  
)  
Application No.: Unknown ) Prior Group Art Unit: 2877  
)  
Filed: June 25, 2003 ) Prior Examiner: H. Pham  
)  
For: OPTICAL SYSTEM ADJUSTING ) Divisional Application of U.S. Patent  
METHOD FOR ENERGY BEAM ) Application Serial No. 09/533,815, filed  
APPARATUS ) March 24, 2000

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. § 1.97(b)**

Pursuant to 37 C.F.R. §§ 1.56 and 1.97(b), applicants bring to the attention of the Examiner the documents listed on the attached PTO 1449. This Information Disclosure Statement is being filed concurrently with the above-identified divisional application.

Copies of the listed documents were previously submitted in a prior application Serial No. 09/533,815, filed March 24, 2000, upon which applicants rely for the benefits provided in 35 U.S.C. § 120. Applicants respectfully request that the Examiner consider the listed documents and indicate that they were considered by making appropriate notations on the attached form.

This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that each or all of the listed documents are material or constitute "prior art." If the Examiner applies any of the

documents as prior art against any claim in the application and applicants determine that the cited document do not constitute "prior art" under United States law, applicant reserves the right to present to the office the relevant facts and law regarding the appropriate status of such documents.

Applicants further reserve the right to take appropriate action to establish the patentability of the disclosed invention over the listed documents, should one or more of the documents be applied against the claims of the present application.

If there is any fee due in connection with the filing of this Statement, please charge the fee to our Deposit Account No. 06-0916.

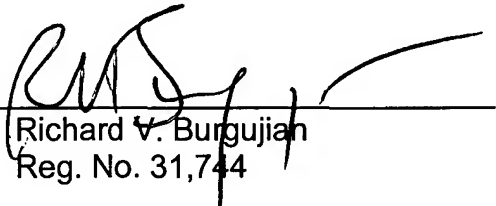
Respectfully submitted,

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Dated: \_\_\_\_\_

6/25/03

By: \_\_\_\_\_

  
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## INFORMATION DISCLOSURE CITATION

Atty. Docket No.	7906.0008-01	Appln. No.	Unknown
Applicant	Ogasawara et al.		
Filing Date	June 25, 2003	Prior Group:	2877

## U.S. PATENT DOCUMENTS

Examiner Initial*	Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate
	5,315,123	5/1994	Itoh et al.			
	5,285,075	2/1994	Minamide et al.			
	5,136,169	8/4/92	Smith et al.			
	4,808,829	2/1989	Okumura et al.			
	4,650,983	3/1987	Suwa			
	4,636,968	1/1987	Gotou et al.			
	4,443,703	4/1984	Shimazu et al.			
	4,376,249	3/1983	Pfeiffer et al.			
	4,199,688	4/1980	Ozasa			

## FOREIGN PATENT DOCUMENTS

Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	Goodberlet et al., "Spatial-Phase-Locked Electron-Beam Lithography with a Delay-Locked Loop," J. Vac. Sci. Technol. (1997), B15(6): 2293-97
	Smith et al., "A New Approach to High Fidelity E-Beam and Ion-Beam Lithography Based on an <i>in situ</i> Global-Fiducial Grid," J. Vac. Sci. Technol. (1991), B9(6):2992-95
	Smith et al., "Application of Moiré Techniques in Scanning-Electron-Beam Lithography and Microscopy," J. Vac. Sci. Technol. (1975), 12: 1262-65

Examiner	Date Considered
*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	
Form PTO 1449	Patent and Trademark Office - U.S. Department of Commerce